

PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of: Jung Wook LIM, et al.

Serial No.: New Application Group Art Unit: Not Yet Assigned

Filed: August 22, 2003 Examiner: Not Yet Assigned

Title: METHOD OF FORMING A THIN FILM IN A SEMICONDUCTOR DEVICE

**INFORMATION DISCLOSURE STATEMENT**

Honorable Commissioner for Patents  
PO Box 1450,  
Alexandria, VA 22313

August 22, 2003

Sir:

As a means of complying with the duty of disclosure under 37 CFR §1.56, and in accordance with 37 CFR §§1.97 and 1.98, Applicant(s), through the undersigned attorney, submits this Information Disclosure Statement. The patents, publications or other information submitted herewith are listed on the attached Form PTO-1449 and copies are attached.

In accordance with 37 CFR §1.97(b)(1) or (2), this Information Disclosure Statement is being filed either within three months of the filing date of the above-identified application, or within three months of the date of entry into the national stage of the above-identified application as set forth in 37 CFR §1.491. Accordingly, no fee is required.

Respectfully submitted,

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## LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT

ATTY. DOCKET NO.: P69084US0 GROUP ART UNIT: Not Yet Assigned  
 SERIAL NO.: Not Yet Assigned FILING DATE: August 22, 2003  
 APPLICANT(S): Jung Wook LIM, et al. TODAY'S DATE: August 22, 2003

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## U.S. PATENT DOCUMENTS

*EXAMINER <u>INITIAL</u>	DOCUMENT NUMBER	DATE	NAME	INT'L CLASS	SUB- CLASS	FILING DATE (If Appropriate)
AA	<u>6,416,822</u>	<u>7/09/02</u>	<u>Chiang, et al.</u>	<u>B05D</u>	<u>3/00</u>	<u>3/19/01</u>
AB	<u>6,468,924</u>	<u>10/22/02</u>	<u>Lee, et al.</u>	<u>H01L</u>	<u>21/31</u>	<u>5/31/01</u>

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## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	SUB- CLASS	TRANSLATION (YES) <u>  </u> (NO) <u>  </u>
AC	<u>2002-46431</u>	<u>06/21/02</u>	<u>KOREA (ROK)</u>	<u>H01L</u>	<u>29/108</u> <u>X</u> <u>  </u>
AD	_____	_____	_____	_____	_____
AE	_____	_____	_____	_____	_____

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## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AF	<u>Jin-Seong Park, et al.; "Plasma-Enhanced Atomic Layer Deposition of Ta-N Thin Films"; Journal of The Electrochemical Society, 149 (1) C28-C32 (2002).</u>
AG	<u>Hyun-Jung Song, et al.; "Increment of the Dielectric Constant of Ta<sub>2</sub>O<sub>5</sub> Thn Films by Retarding Interface Oxide Growth on Si Substrates"; Electrochimica and Solid-State Letters, 4(7) F13-F14 (2001).</u>

EXAMINER

DATE CONSIDERED

\* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).